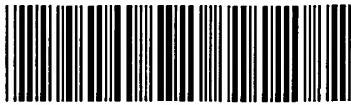


**Search Notes**

Application No.

10/603,743

Examiner

D. Rutledge

Applicant(s)

KAMIYA, SABURO

Art Unit

2851

**SEARCHED**

Class	Subclass	Date	Examiner
355	30, 53, 55	1/24/2005	DR
430	5, 50, 31	1/24/2005	DR

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner
355	30, 53	1/24/2005	DR
430	5, 311	1/24/2005	DR

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
lithograph\$2 or microlithograph\$2 or photolithograph\$2; support\$2 or hold\$3 or guid\$3; movable or driv\$3 or moved or moving	1/24/2005	DR
reflective; moves; object or wafer or mask or retice; measur\$4 or interferomet\$4; hold\$3 or support; temperature; adjust\$4	1/24/2005	DR
regulat\$3 or control\$4 or chang\$3; air or gas	1/24/2005	DR